





# **SEMINAR SERIES**

## **Prof. Dr. Jens Gobrecht**

Laboratory for Micro- and Nanotechnology Paul Scherrer Institut, Villigen, Switzerland

### **Synchrotron-based EUV radiation for** nanolithography and actinic mask inspection

Wednesday, May 11, 2016 Time: 17:15-18:15

University of Fribourg, Department of Physics,

#### Small Auditorium 0.51

### www.bioinspired-materials.ch





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